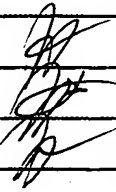
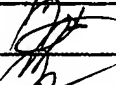
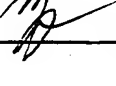


FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTORNEY DOCKET NUMBER 024808-00014	NEW PATENT APPLICATION
LIST OF REFERENCES CITED BY APPLICANT  (Use several sheets if necessary)		APPLICANT Kazunari HONMA, et al.	
		FILING DATE August 1, 2003	GROUP

## U.S. PATENT DOCUMENTS

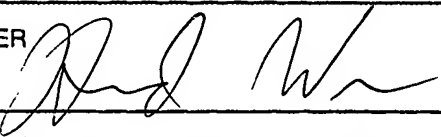
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION YES NO PART.		
	AG	11-068057	March 9, 1999	Japan					X
	AH	2001-072416	March 21, 2001	Japan					X
	AI	11-080181	March 26, 1999	Japan					X
	AJ								
	AK								
	AL								

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

	AM	Item I "Low Temperature Deposition Material" Section 4 "New Deposition Material" Ferroelectric Memory Advanced Process September 13, 1999
	AN	
	AO	

EXAMINER 	DATE CONSIDERED 11/4/05
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	